

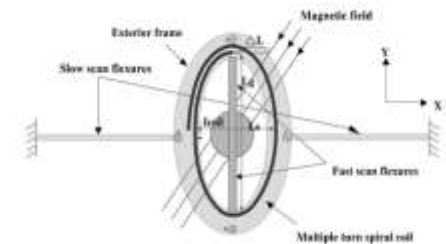
A Predictive Control Scheme for Electromagnetic Scanning Micro-mirrors

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- MEMS electromagnetic scanning micro-mirror (ESMM) is an optical actuator used in optical-electro-mechanical instrument.
- The ESMM is a micro-opto-electro-mechanical system with complex characteristics.
- A predictive control scheme is proposed for angular control of electromagnetic scanning micro-mirrors.



MEMS micro-mirror control platform